



TO
AF

**RESPONSE UNDER 37 C.F.R. § 1.116
EXPEDITED PROCEDURE REQUESTED
EXAMINING GROUP 1795**

OK TO ENTER: /SR/

03/11/2008

PATENT

Attorney Docket No. 04329.3304-00

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Ayako NAKANO et al.

Application No.: 10/823,539

Filed: April 14, 2004

For: PATTERN FORMING METHOD AND
SYSTEM, AND METHOD OF
MANUFACTURING A
SEMICONDUCTOR DEVICE

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) Group Art Unit: 1795
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) Examiner: Stephen D. ROSASCO
)
) Confirmation No.: 4440
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Mail Stop AF

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

REQUEST FOR RECONSIDERATION

In reply to the final Office Action mailed November 6, 2007, the period for response to which extends through February 6, 2008, Applicants respectfully request reconsideration of the above-identified application in light of the following remarks.